## **WEST Search History**

Hide Items Restore Clear Cancel

DATE: Wednesday, September 01, 2004

Hide? Set Name Query			Hit Count
DB = PGPB, USPT, USOC, EPAB, JPAB, DWPI, TDBD; PLUR = YES; OP = OR			
	L14	L13 and (reactor or chamber)	1783
	L13	ONO and plasma	5615
	L12	L9 and (deposit\$4 with onto with nitride)	0
	L11	L9 and (deposit\$4 with on with nitride)	0
	L10	L9 and (deposition adj chamber)	379
	L9	plasma and (deposit\$4 with (direct\$4 or contact\$4) with nitride)	3156
	L8	plasma and (deposit\$4 with (direct\$4 or contact\$4) with nitride)	3156
	DB=US	SPT; PLUR=YES; OP=OR	
	L7	L6 and (deposition adj chamber)	368
	L6	(plasma with nitride) and (plasma with oxide)	5771
	L5	L4 and 0.6	26
	L4	(oxidation adj rate) same nitride	272
	L3	L2	0
	L2	(wet adj RTO) same rate same nitride	0
	L1	(wet adj RTO) same rate same nitride same silicon	0

**END OF SEARCH HISTORY**